

# Transparent Conducting Oxide Electrodes

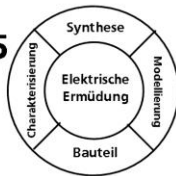
## Grain boundary scattering in undoped and doped $\text{In}_2\text{O}_3$

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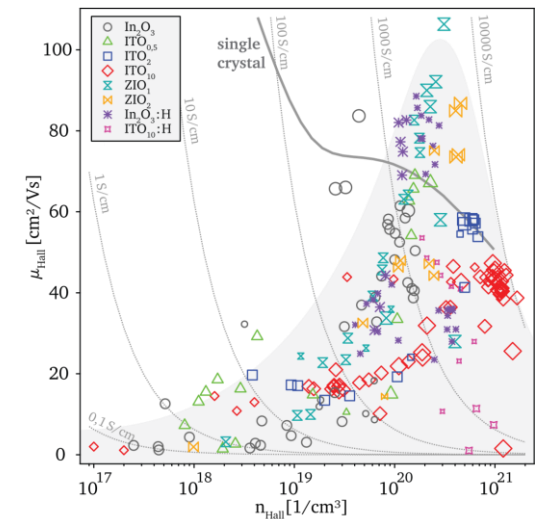
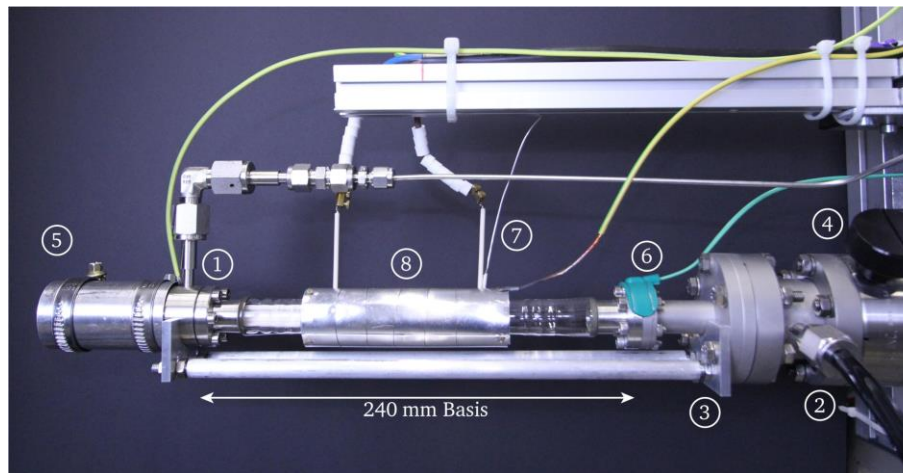
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SFB 595

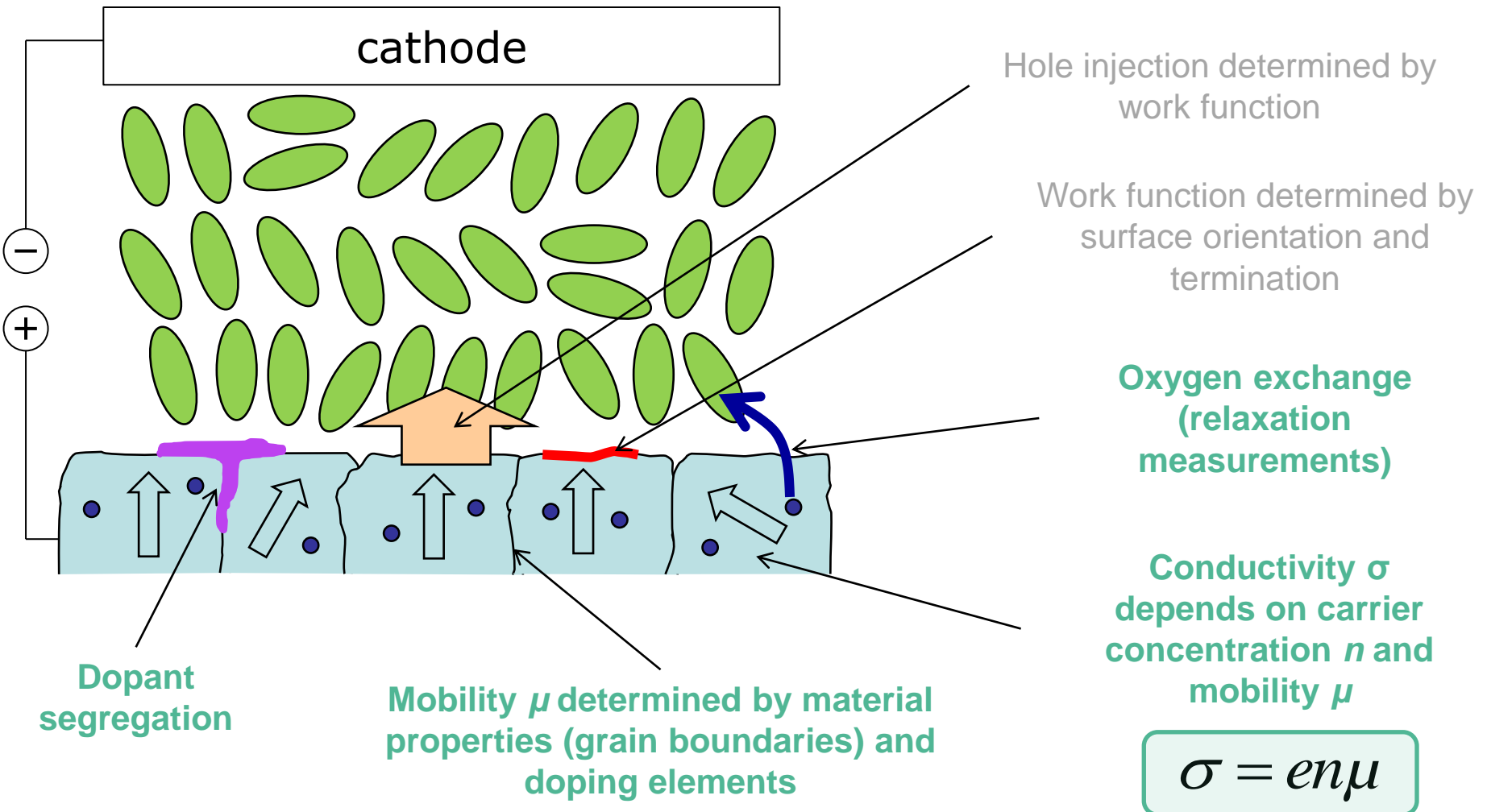
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DFG

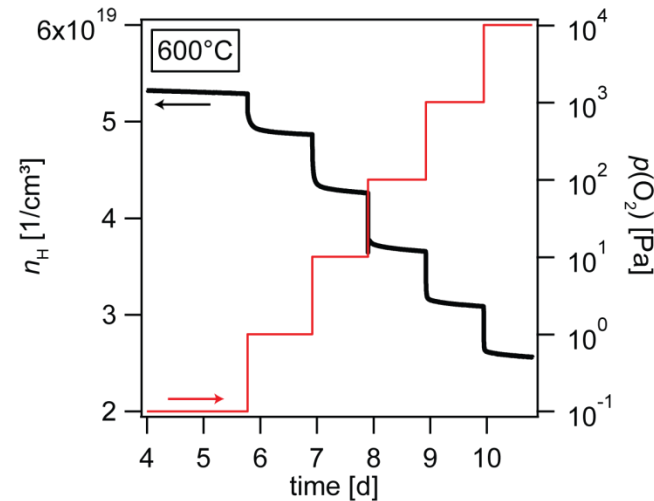


# Motivation: The TCO electrode for organics

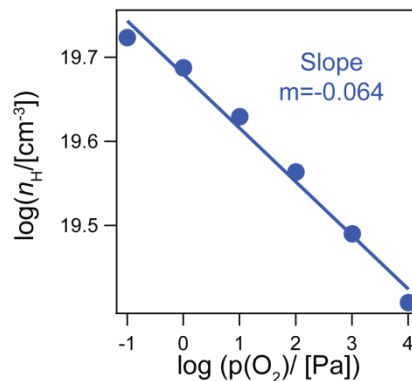
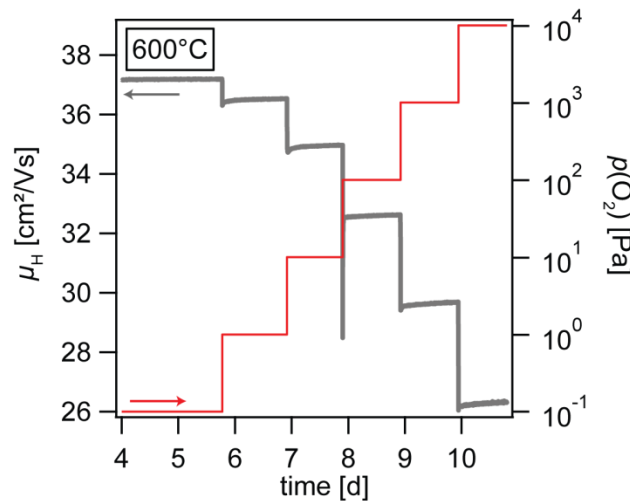


# $p(\text{O}_2)$ dependent Hall-relaxation measurement of undoped $\text{In}_2\text{O}_3$

## Carrier concentration

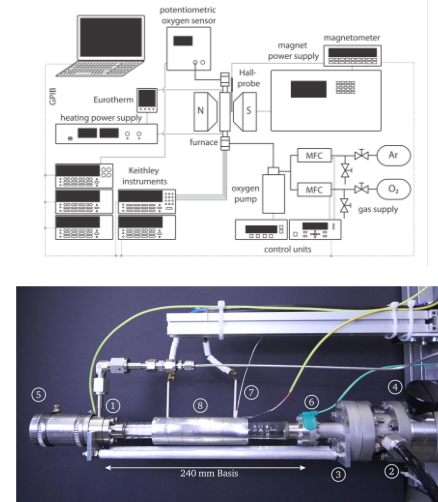


## Carrier mobility

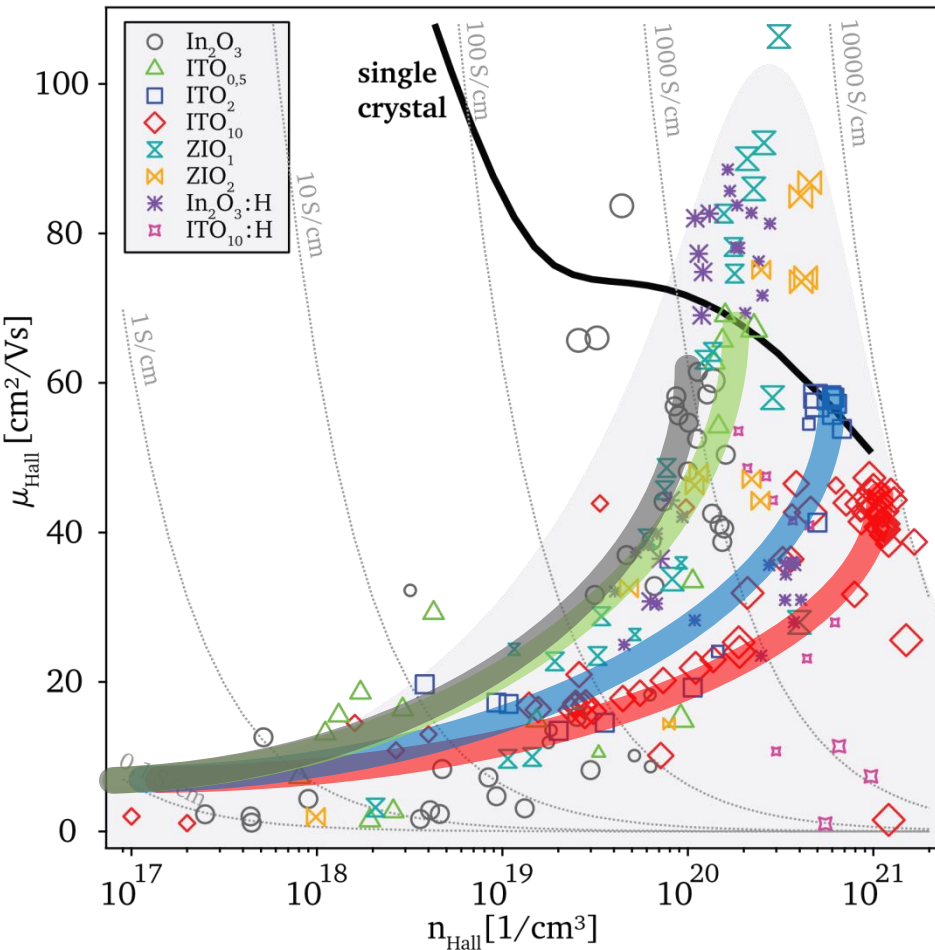


- Carrier concentration  $n$  changes reversibly with oxygen partial pressure
  - Slope of Brouwer plot does not correspond to expected  $p(\text{O}_2)^{-1/6}$  dependence
- Carrier mobility  $\mu$  also depends on oxygen partial pressure:
  - due to changes in carrier concentration and changes in **grain boundary barrier** ???

## Setup



# Influence of doping elements on $\text{In}_2\text{O}_3$



Element	Short	Concentr.	Purpose
Sn	ITO	0.5, 2, 10 wt% $\text{SnO}_2$	Most used, Segregation effects?
Zr	ZIO	1, 2 wt% $\text{ZrO}_2$	High mobility
H	$\text{In}_2\text{O}_3:\text{H}$		High mobility, low processing T

Scattering mechanisms in  $\text{In}_2\text{O}_3$ :

- Phonon Scattering
  - Ionized Impurity Scattering
  - Grainboundary Scattering
- } Single crystal (O. Bierwagen)

For  $n < 10^{20} 1/\text{cm}^3$   $\mu$  is decreasing:

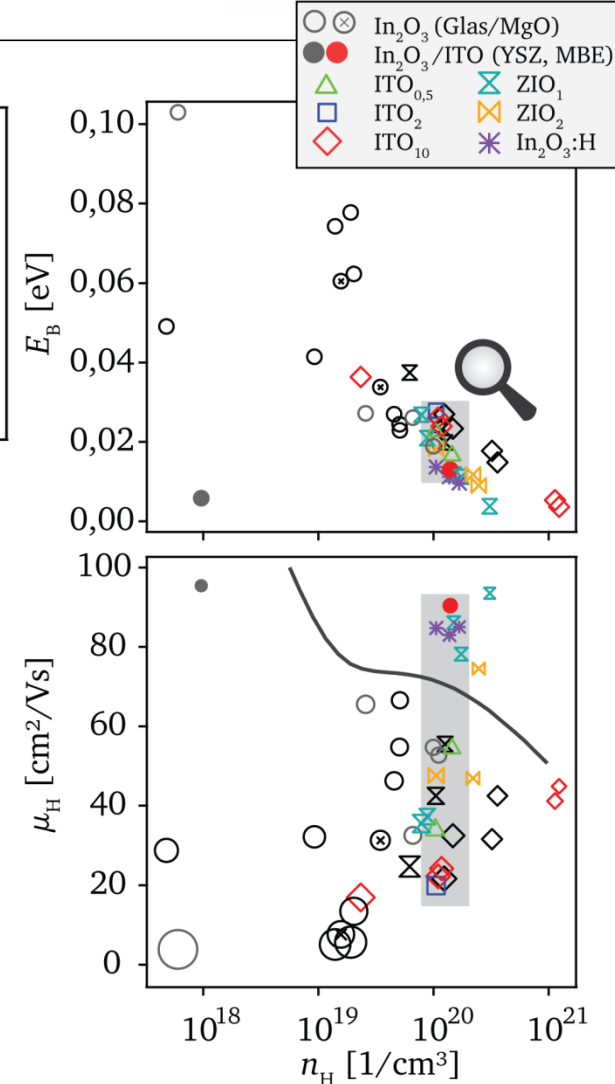
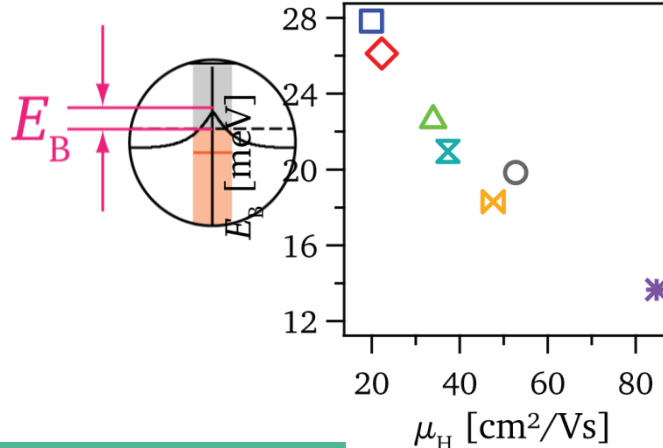
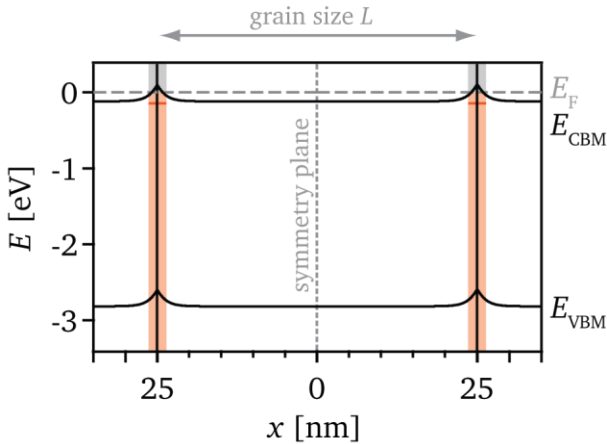
- effect of grainboundary scattering

Different dopings behave differently

- Segregation at grain boundaries?

Cooperation with O. Bierwagen, Paul-Drude-Institut, Berlin

# GB Scattering – measured barriers



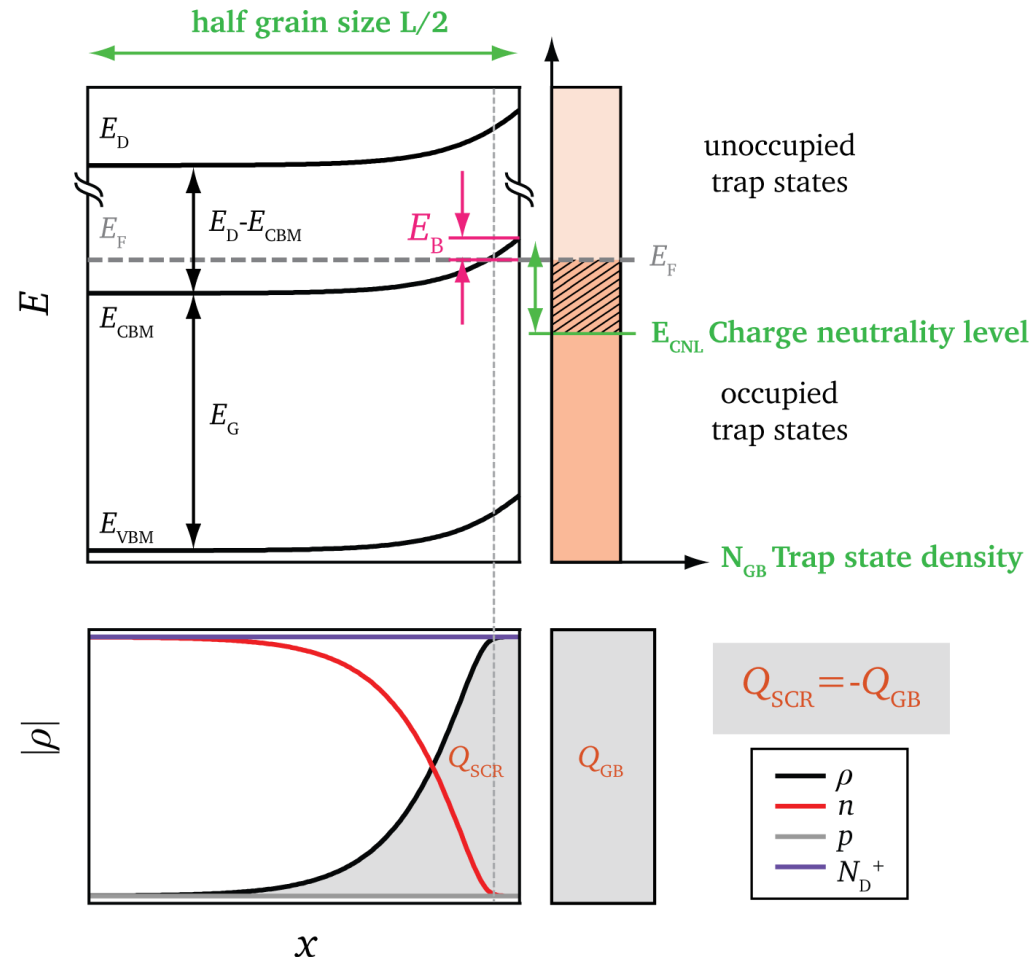
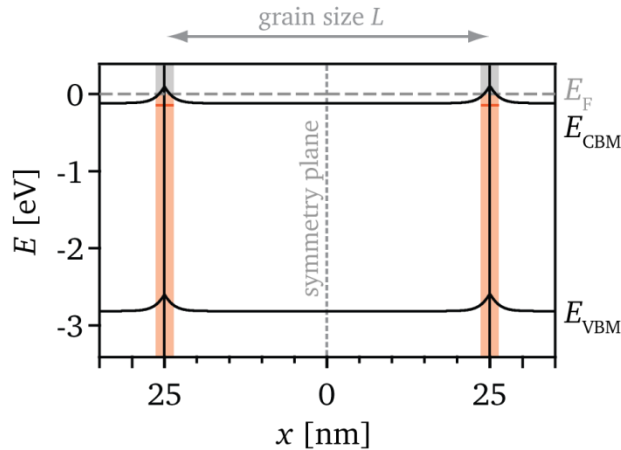
$$\mu_{GB}(T) = \mu_{0,300 K} \cdot \left( \frac{T}{300 K} \right)^{-\beta} \cdot \exp \left( -\frac{E_B}{k_B T} \right)$$

Barriers  $E_B$ ...

- were successfully measured
- increase with decreasing  $n$
- are higher for ITO than for ZIO and In<sub>2</sub>O<sub>3</sub>:H

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# GB Scattering – Simulation: model



## Literature

- „Setos modell“ was used:  
Not valid for degenerate semiconductors

## Novel model needed

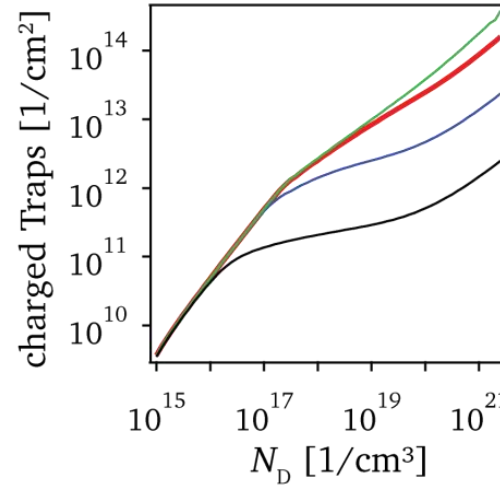
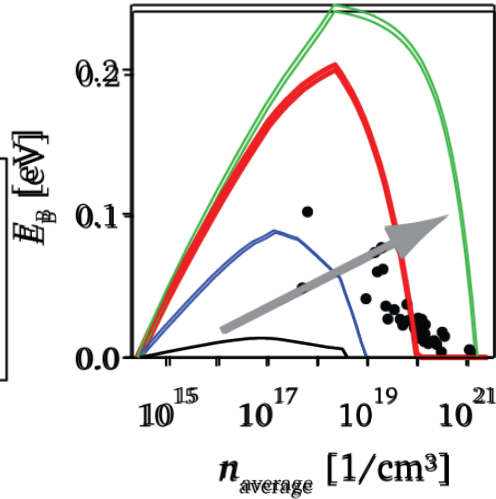
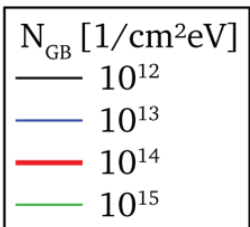
- Solving Poissons equation numerically

$$\rho(x) = -\epsilon_0 \epsilon_s \frac{d^2 \phi(x)}{dx^2} = \epsilon_0 \epsilon_s \frac{d \mathcal{E}(x)}{dx}$$

- MATLAB simulation
- Parameters  $E_{CNL}$ ,  $N_{GB}$ ,  $L$

# GB Scattering – Simulation: results

Variation  
of  $N_{GB}$



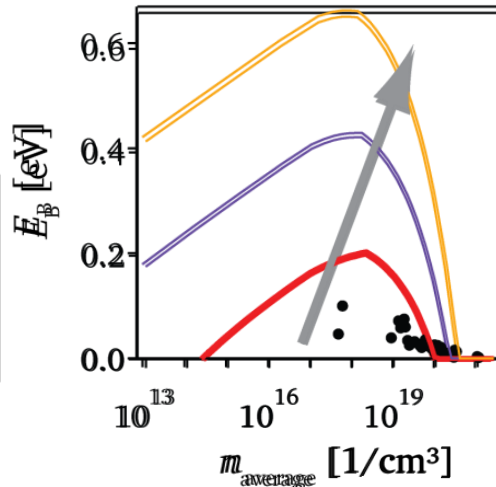
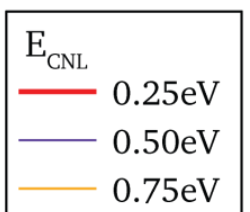
**Standard Parameters**

$$E_{CNL} = 0.25 \text{ eV}$$

$$N_{GB} = 10^{14} / \text{cm}^2 \text{eV}$$

$$\text{Grain size } L = 50 \text{ nm}$$

Variation  
of  $E_{CNL}$



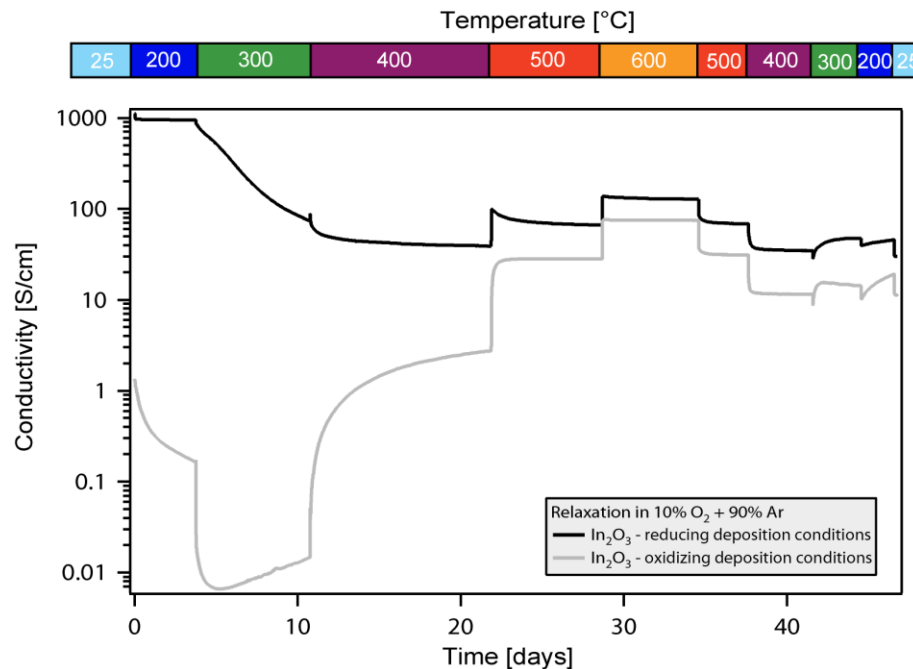
Model overdetermined for high  $n$ :  
 $N_{GB}$  and  $E_{CNL}$  change position of onset



lower  $n$  necessary to measure maximum



# THE experiment



## Sample:

Undoped In<sub>2</sub>O<sub>3</sub> thin film deposited at oxidizing conditions

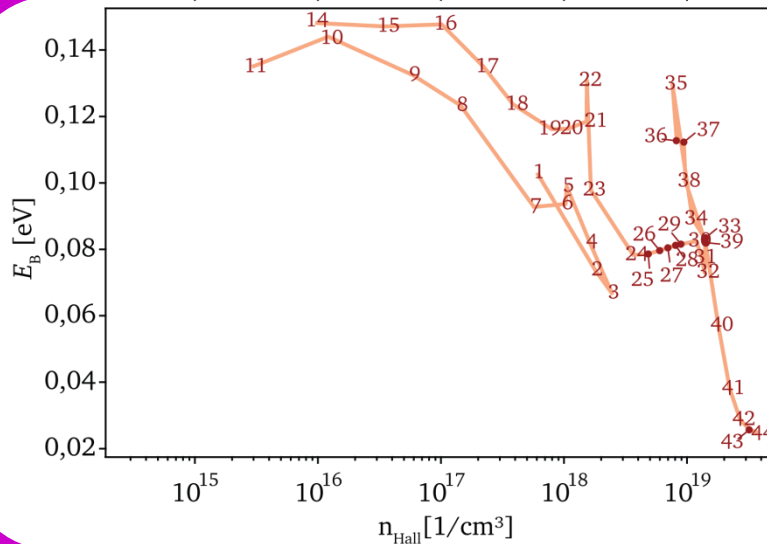
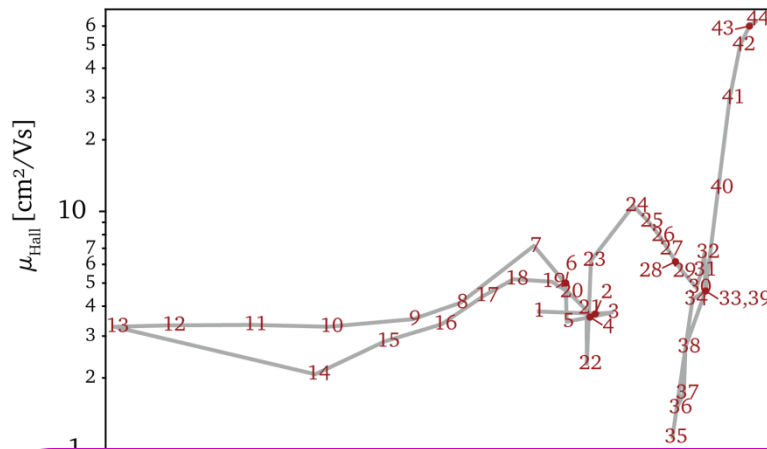
## Relaxation measurement:

1. T-dependent
2. p(O<sub>2</sub>)-dependent at 600°C

Cooling to RT after short time annealing and measurement of E<sub>B</sub>



# THE experiment - result



## Sample:

Undoped In<sub>2</sub>O<sub>3</sub> thin film deposited at oxidizing conditions

## Relaxation measurement:

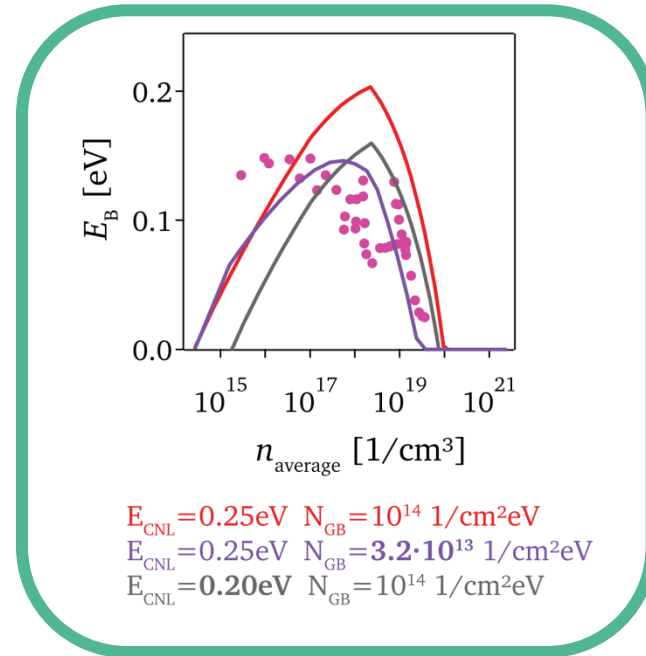
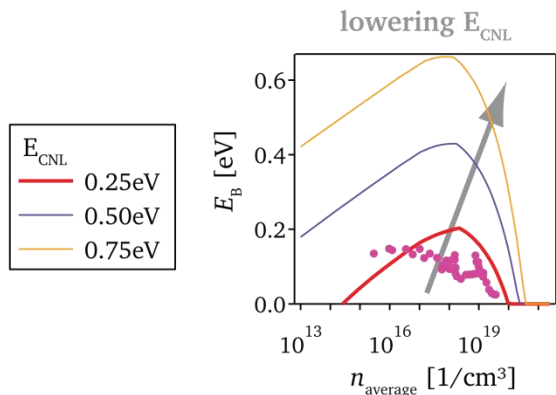
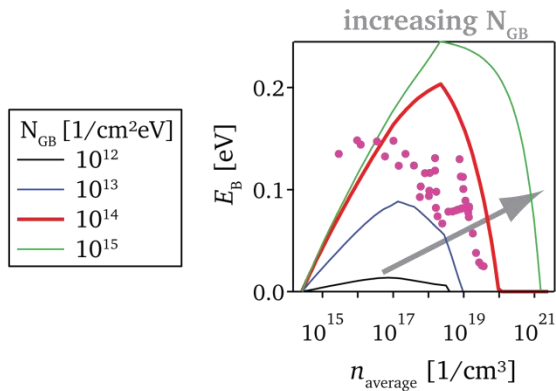
1. T-dependent
2. p(O<sub>2</sub>)-dependent at 600°C

Cooling to RT after short time annealing and measurement of  $E_B$

**Total measurement time:  
62 days**

# Comparison of measurement and simulation

**Standard Parameters:**  $E_{\text{CNL}} = 0.25\text{eV}$   
 $N_{\text{GB}} = 10^{14} \text{ 1/cm}^2\text{eV}$   
 Grain size  $L = 50\text{nm}$



Approximate  $E_{\text{CNL}}$  and  $N_{\text{GB}}$  can be determined  
 $E_{\text{CNL}}$ :  $0.15\text{eV}$  to  $\sim \text{max. } 0.3\text{eV}$   
 $N_{\text{GB}}$ :  $0.3 - 1 \cdot 10^{14} \text{ 1/cm}^2\text{eV}$

# Summary

- **Novel setup** for T and  $pO_2$  dependent Hall-effect measurement was constructed
- $In_2O_3$  was doped with **Sn, Zr and H**: carrier concentration and mobility were analyzed
- **Grain boundary barriers  $E_B$**  were measured: doping element affects  $E_B$
- Grain boundary scattering **model** was developed and grain barrier height simulated
  - **One  $In_2O_3$  sample** was measured about large carrier concentration region:  $E_{CNL}$  and  $N_{GB}$  can be simulated (first time!)

**Thank you very much for your attention!**